## ABSTRACT OF THE DISCLOSURE

A wafer processor includes a matching apparatus for detecting an approximate region approximated to a predetermined template image from an input image.  The matching apparatus includes input signal generating means for generating a first input signal and a second input signal representing pixel values of an input image projected, respectively, on a first axis and a second axis, first axis/first section detecting means for detecting a first axis/first section including an approximate region in the first axis direction from an input image, second axis/first section detecting means for detecting the second axis/first section including an approximate region in the second axis direction, and candidate region signal generating means for generating a third input signal representing the pixel value of the candidate region image projected on the first axis in the input image specified by the first axis/first section and the second axis/first section projected on the first axis, and first axis/second section detecting means for detecting the first axis/second section including an approximate region in the first axis direction.